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Atty. Dkt. No. AMAT/3417/ETCH/SILICON/MBE

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Box Patent Application
Commissioner of Patents and Trademarks
Washington, D.C. 20231

Re: Inventor(s): SONGLIN XU, ZHIWEN SUN, DRAGAN PODLESNIK, XUEYU QIAN
Title: NEW METHODOLOGIES TO REDUCE PROCESS SENSITIVITY TO THE CHAMBER CONDITION

Transmitted herewith is the patent application identified above, including:

- ☒ Specification, claims and abstract, totaling 28 pages.
- ☒ Drawings totaling 6 pages, ☒ Formal ☐ Informal.
- ☒ Executed Declaration and Power of Attorney.
- ☒ Information Disclosure Statement w/ Form 1449 and References.
- ☒ Assignment of the invention to Applied Materials, Inc.
- ☒ Assignment Recordation Cover Sheet



FEE CALCULATION

Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	29	-20=	9	x \$18.00	162.00
Independent Claims	6	-3=	3	x \$78.00	234.00
Basic Filing Fee				\$760.00	\$ 760.00
TOTAL FEES					\$1,156.00

☒ The Commissioner is hereby authorized to charge \$1,156.00 to Deposit Account No. 01-1651/AMAT/3417/ETCH/SILICON/MBE.

☒ The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 01-1651/AMAT/3417/ETCH/SILICON/MBE. A duplicate copy of this transmittal is enclosed.

☒ Please address all future correspondence to:

PATENT COUNSEL
APPLIED MATERIALS, INC.
Legal Affairs Department
P.O.BOX 450A
Santa Clara, CA. 95052

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Commissioner of Patents and Trademarks, Washington, D.C. 20231.

Express Mail Receipt No. EL266338678US

Date of Deposit 7-12-99

Signature

Respectfully submitted,

Robert W. Mulcahy
Registration No. 25,436